

A novel High Average Power High Brightness Soft X-ray Source using a Thin Disk Laser System for optimized Laser Produced Plasma Generation

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H. Legall, B. Kanngießer and H. Stiel

Outline

1. Motivation
2. Laser system
3. LPP setups
 1. Liquid jet technology
 2. Rotating cylinder target

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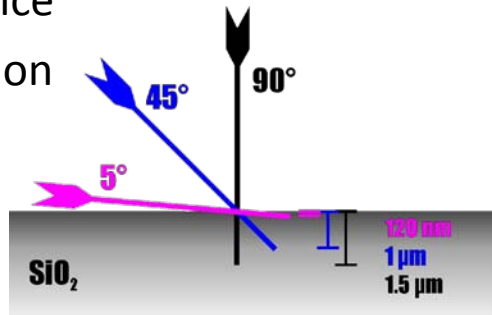
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1 Motivation: soft X-rays

X-ray emission spectroscopy

Grazing incidence
for nm-resolution

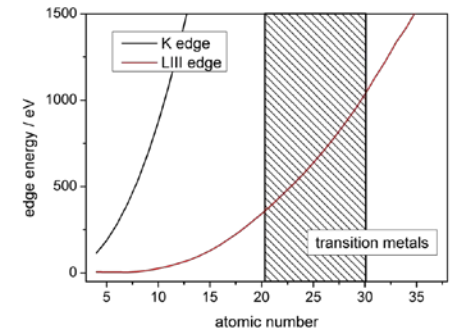
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X-ray absorption spectroscopy

L-edges of transition
metals in solution
Biological samples

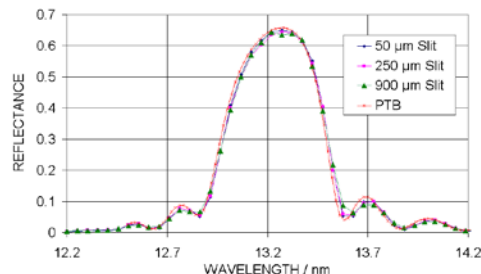
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EUV metrology

Reflectivity
Foil thickness

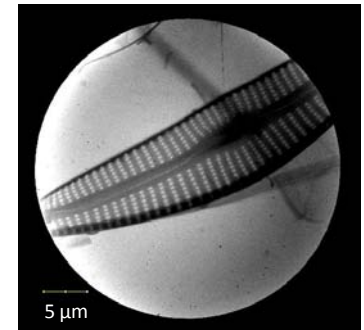
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Imaging

Microscopy in the water
window
Coherent imaging
Holography

...



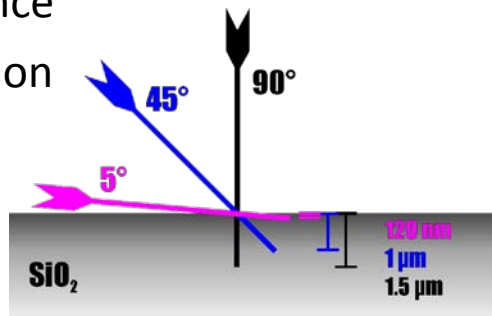
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1 Motivation: soft X-rays

X-ray emission spectroscopy

Grazing incidence
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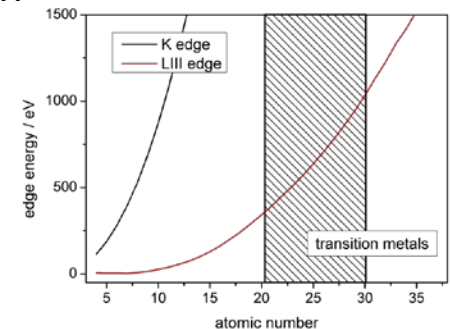
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X-ray absorption spectroscopy

L-edges of transition
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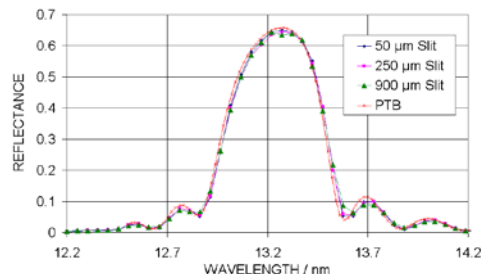
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EUV metrology

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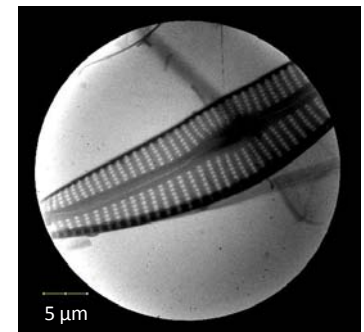
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Imaging

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Goal: lab-based equipment

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2 Pump Laser

High brilliance:

1. High single shot intensity
2. High repetition rate
3. Good beam quality & stability

⇒ diode-pumped YAG-laser systems
slab system thin disk laser system

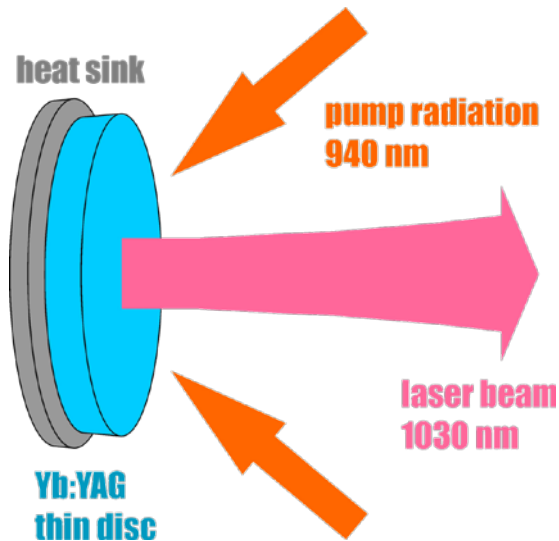
2 Pump Laser

High brilliance:

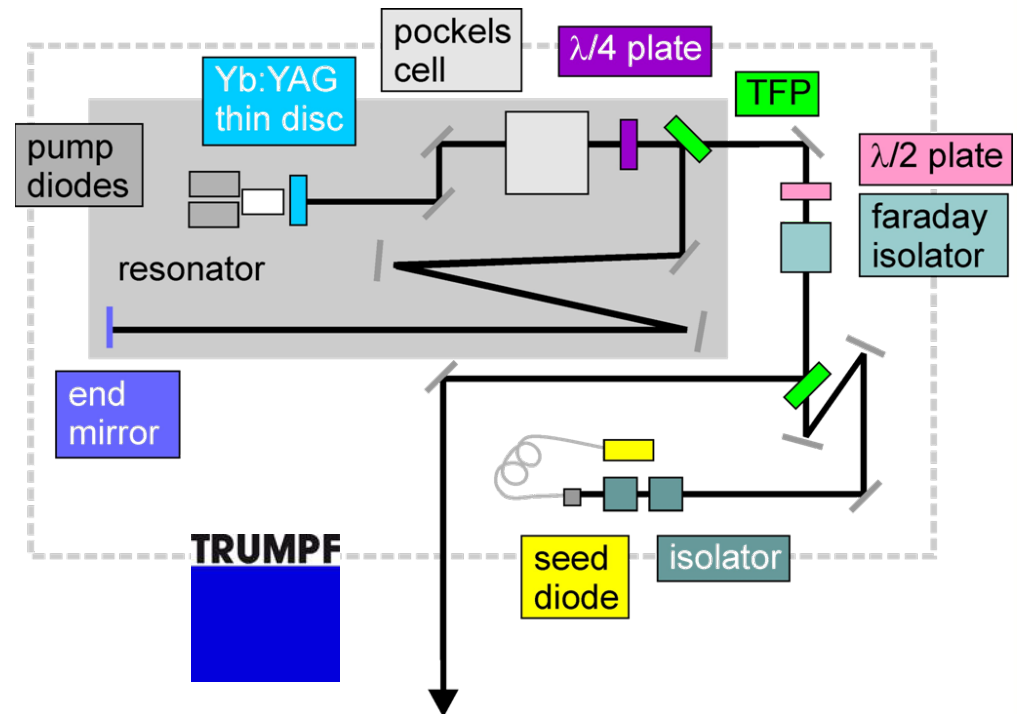
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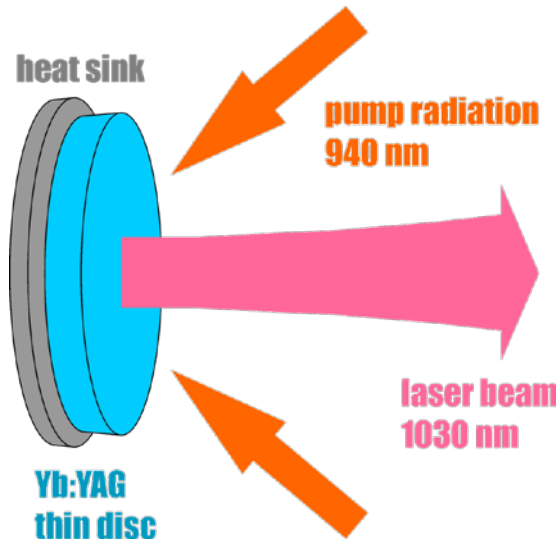
2 Laser system



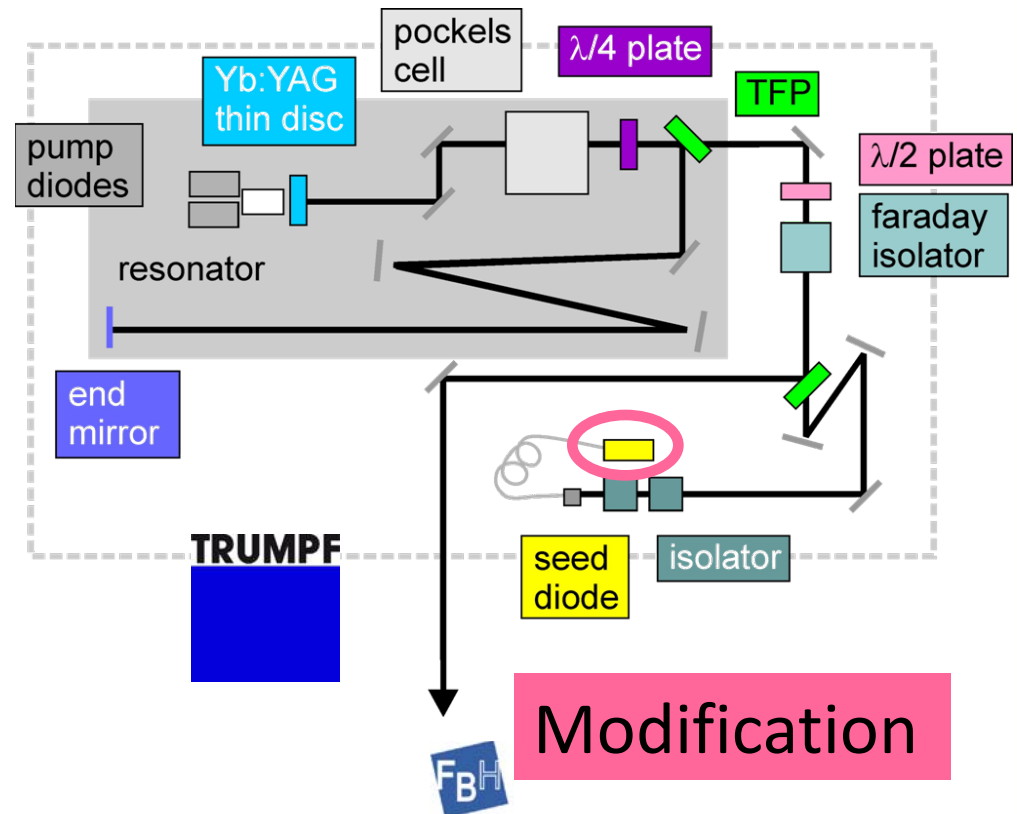
pulse energy	220 mJ
pulse duration	10 ns
repetition rate	>100 Hz
mean power	> 15 W
M^2	<1.2



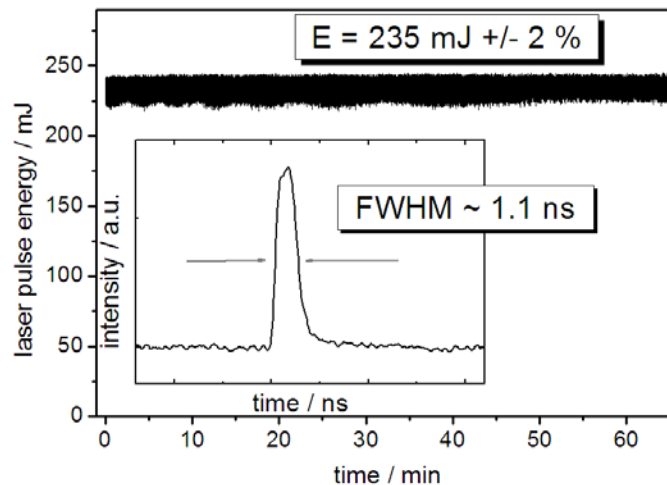
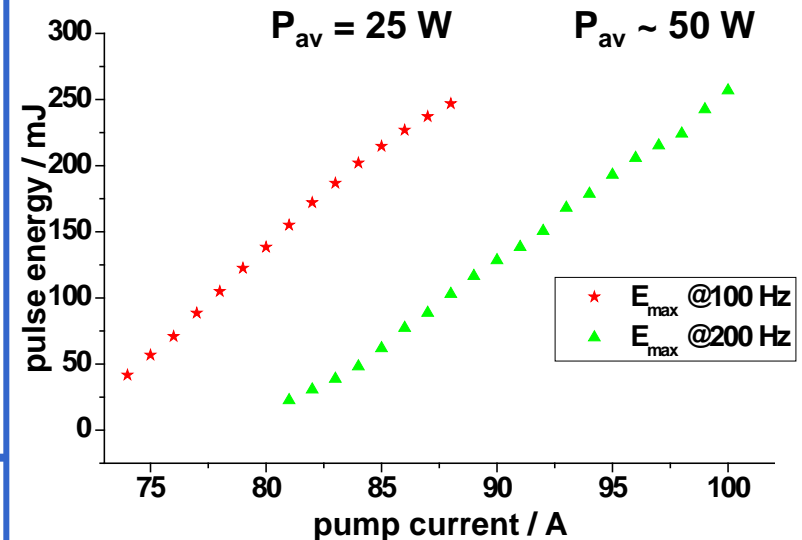
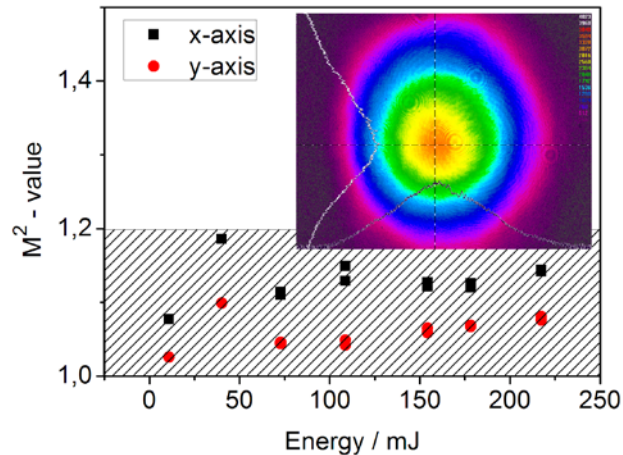
2 Laser system



pulse energy	220 mJ
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2 Beam characteristics

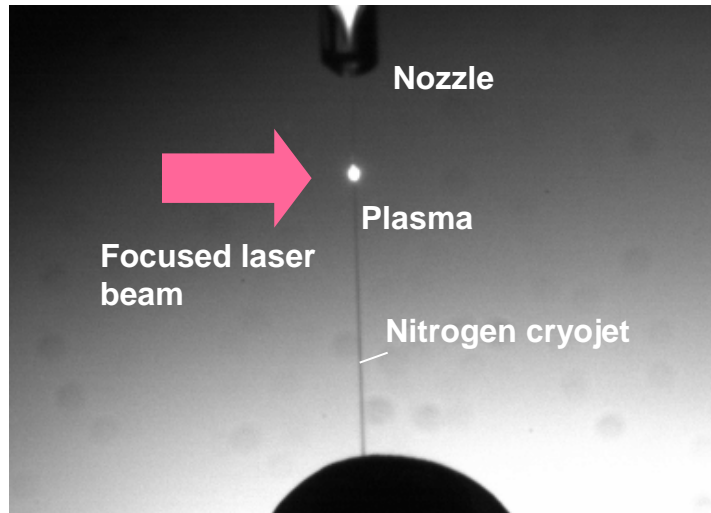


Stable performance:
235 mJ @ 1.1 ns
Regenerative system:
shorter pulse durations
possible

Outline

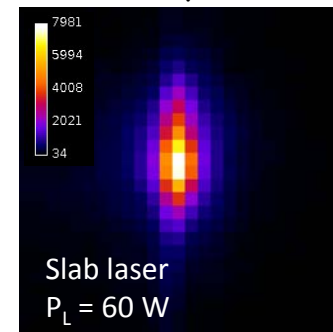
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3.1 Liquid jet system

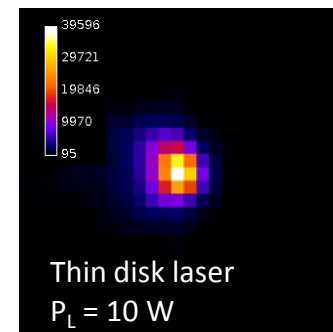


Source size

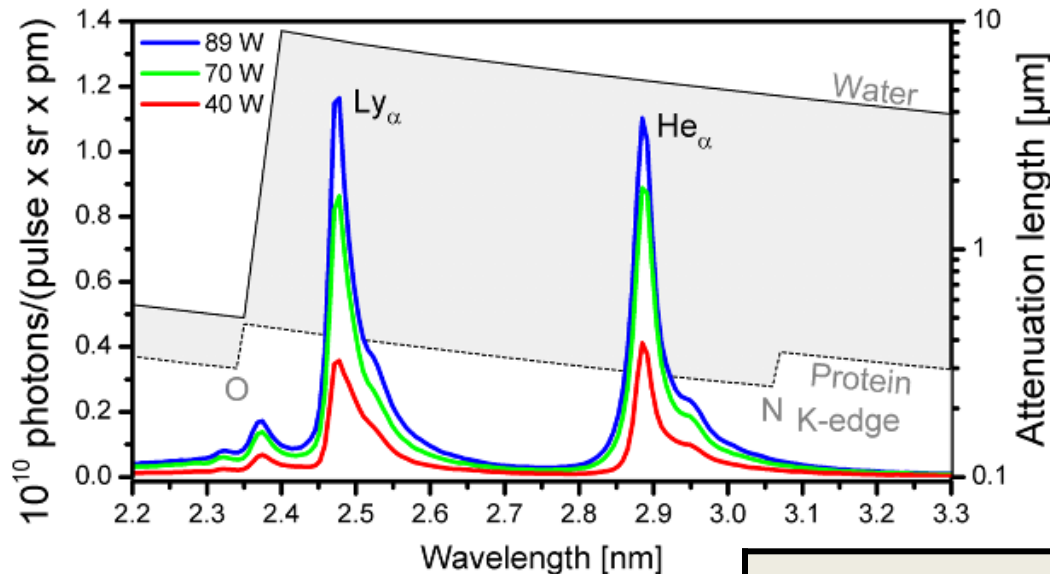
Slab laser
 $18 \times 40 \mu\text{m}$



Thin disk laser
 $18 \times 21 \mu\text{m}$



3.1 Liquid jet system



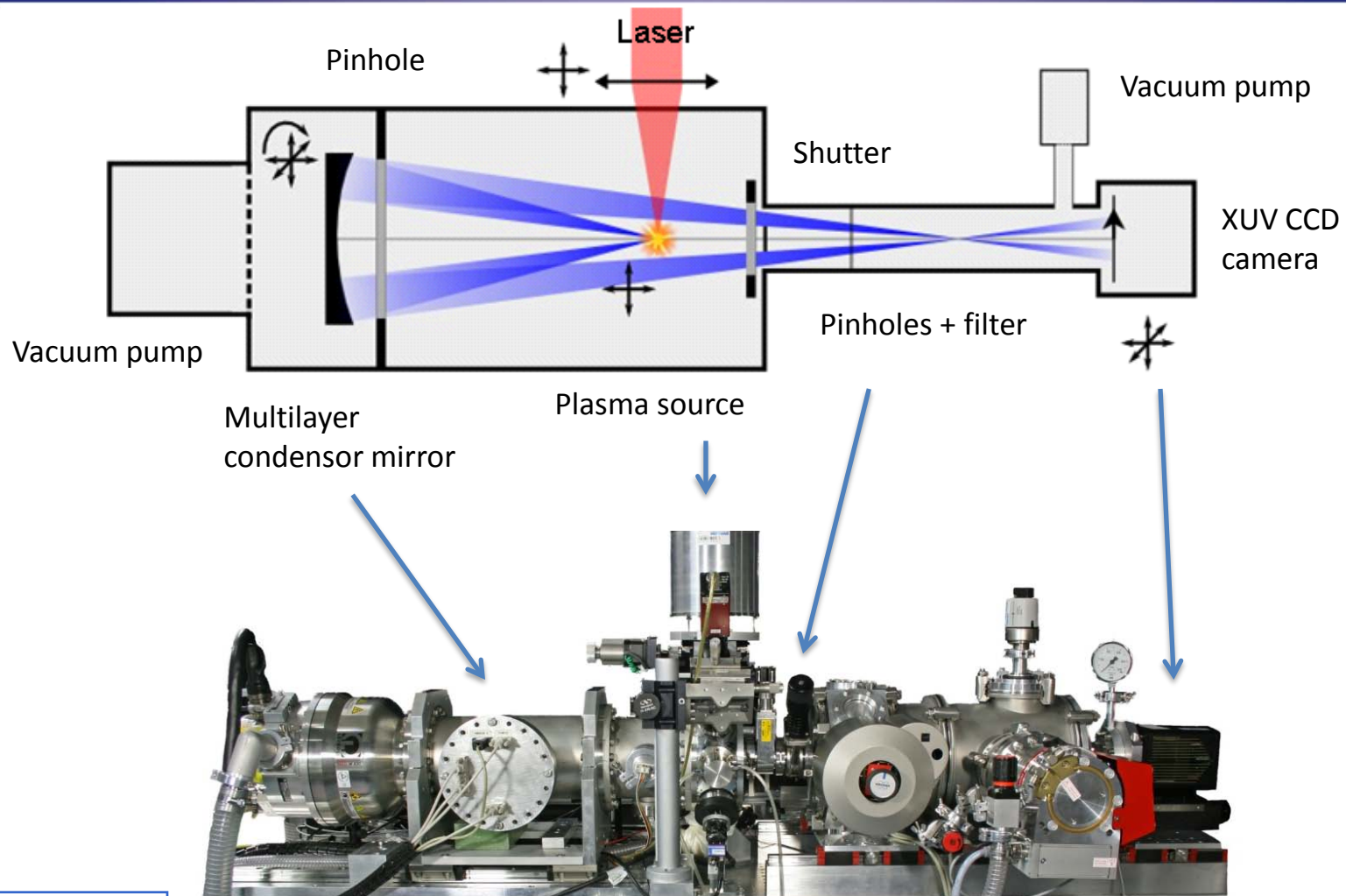
→ for EUV imaging and metrology:

use water jet instead of liquid nitrogen !*

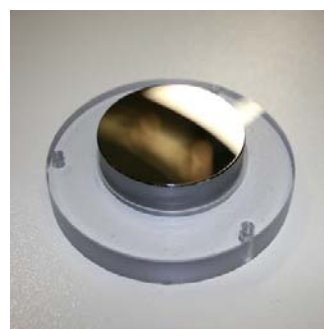
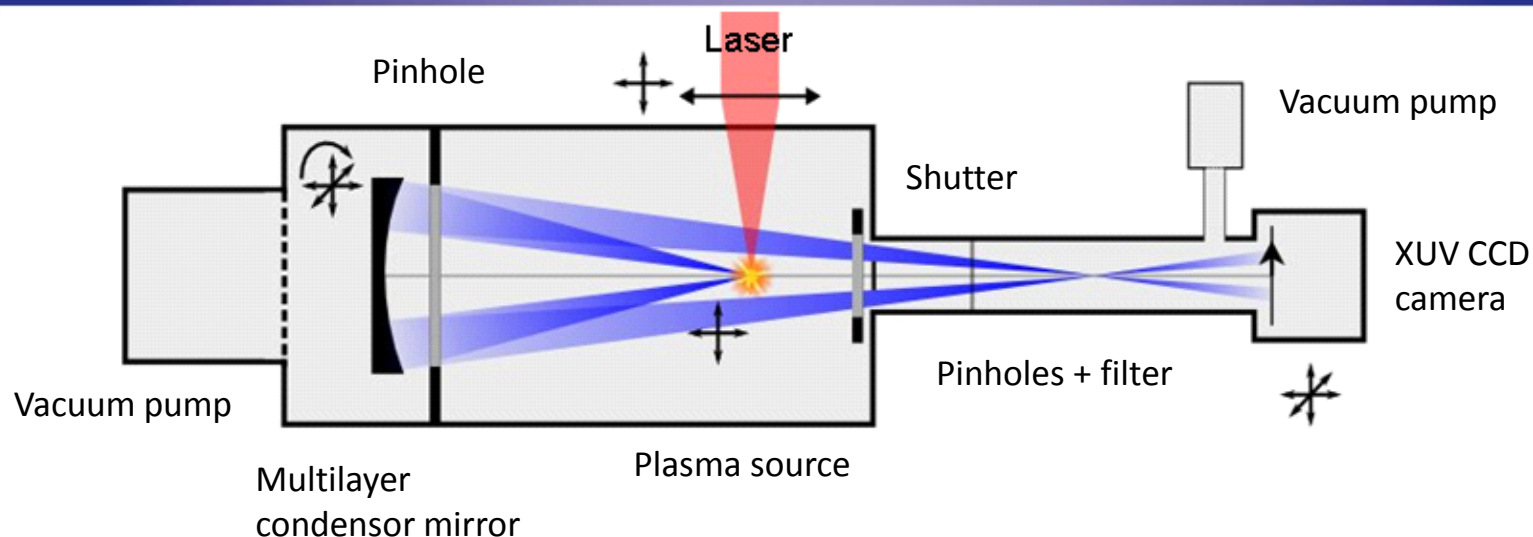
	Slab laser	Thin disk laser (100 Hz)
E (mJ)	65	170
τ (ps)	450	1000
P (W)	90	17
ph/ s sr	$6 \cdot 10^{14}$	$7 \cdot 10^{13}$
ph/s mrad ² mm ²	$8 \cdot 10^{11}$	$2 \cdot 10^{11}$

* H. Stiel, U. Vogt et al. SPIE, 4343, 535 (2001)

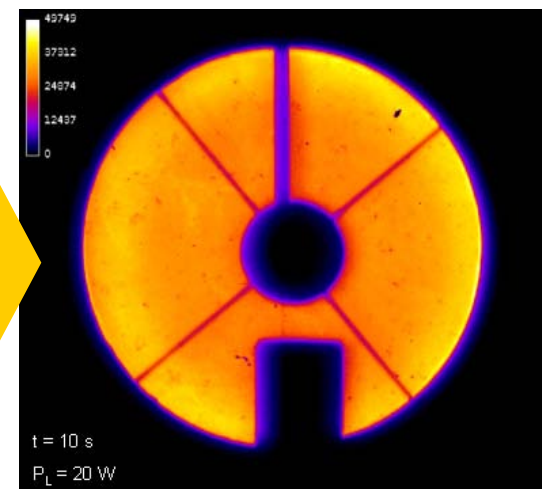
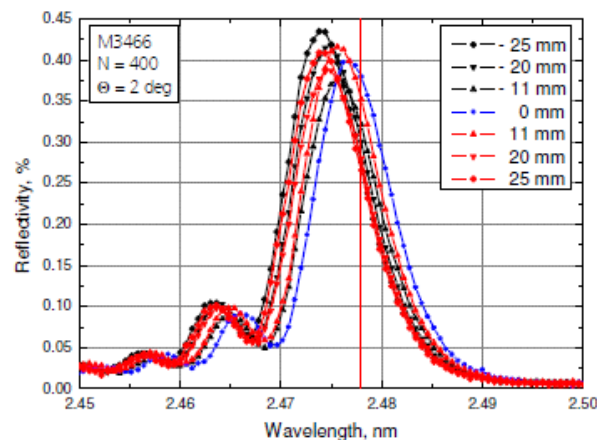
3.1 X-ray microscope



3.1 X-ray microscope



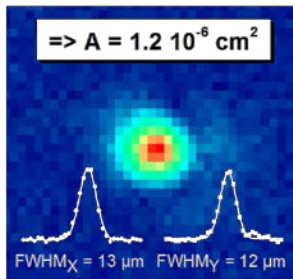
Fraunhofer
IOF



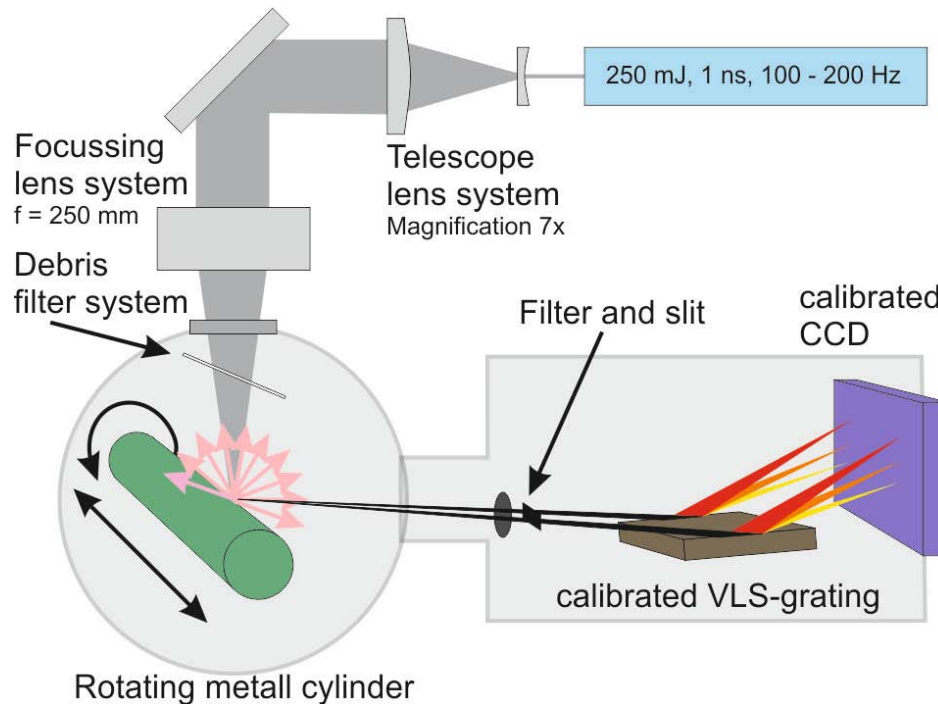
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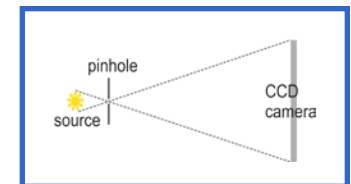
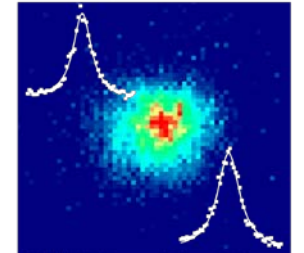
3.2 Cylinder target



Optimal
heating for 2 nm

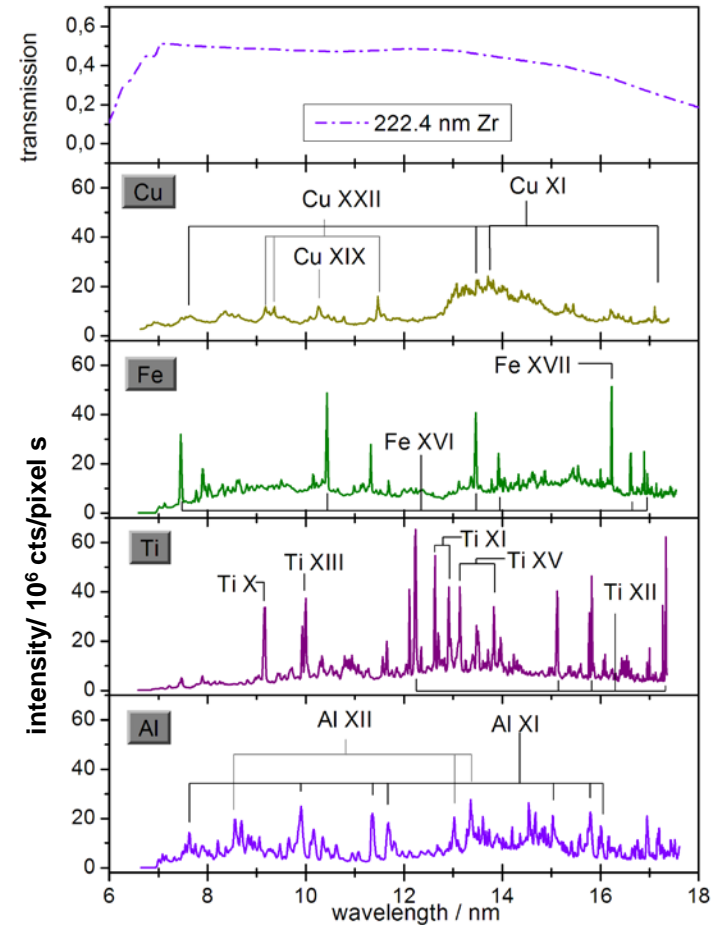
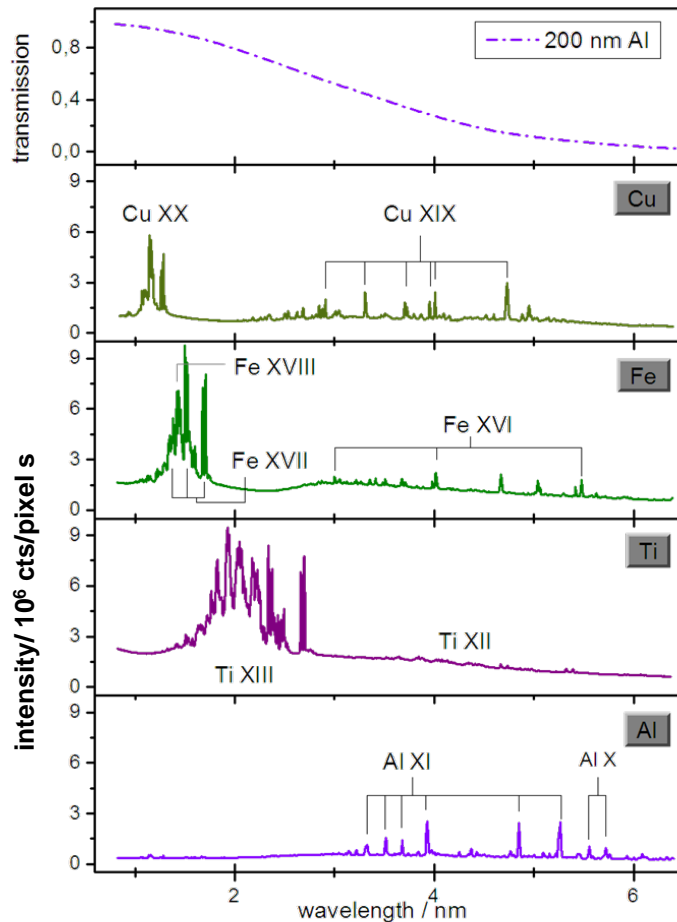


FWHM[y-axis] = 30 μm

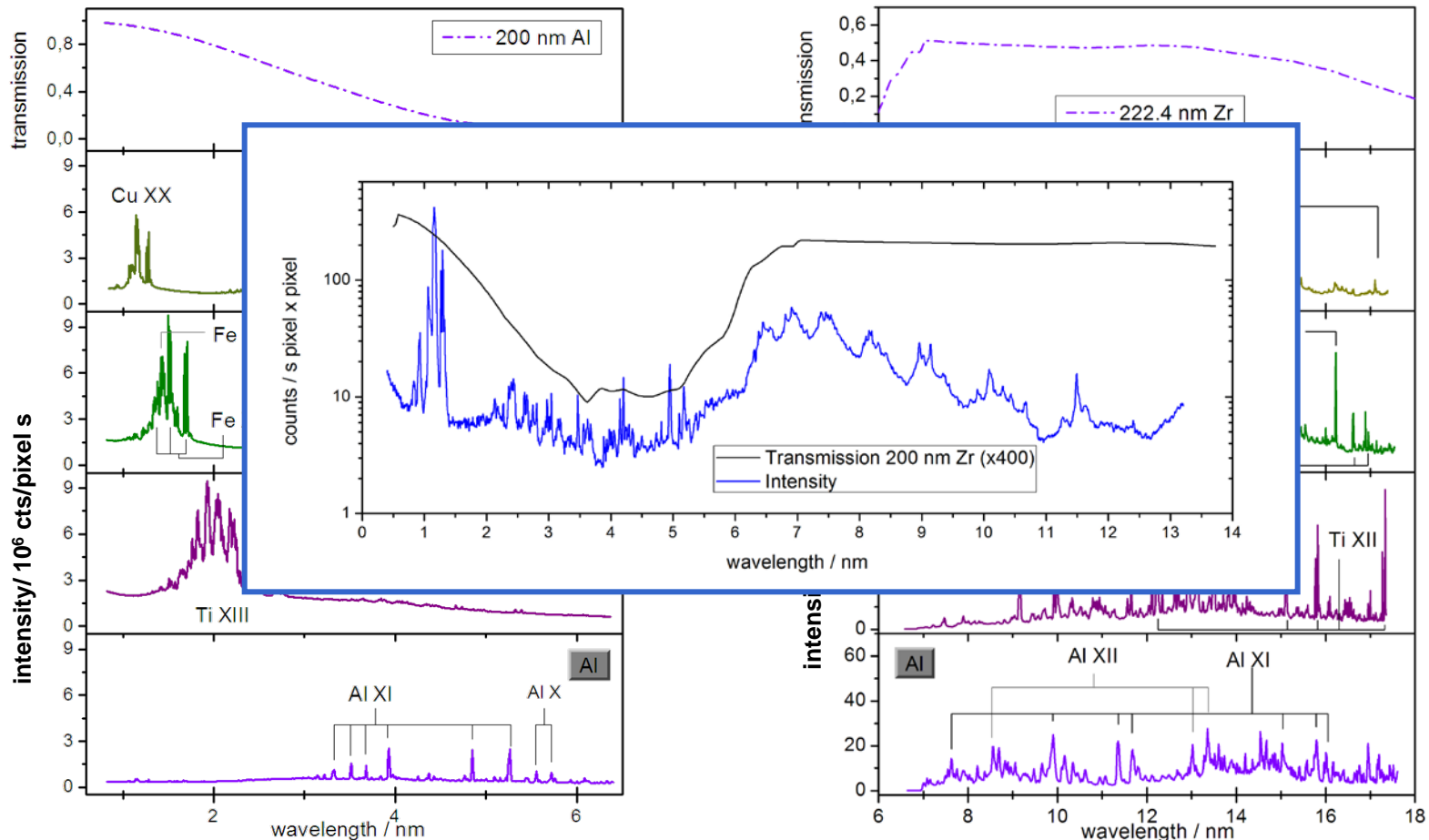


Variable-line spaced grating spectrograph
& Transmission grating spectrograph

3.2 EUV/XUV spectra

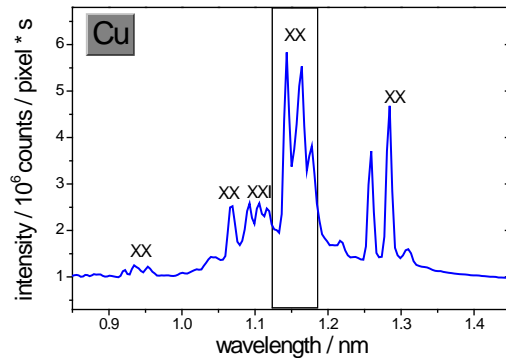


3.2 EUV/XUV spectra

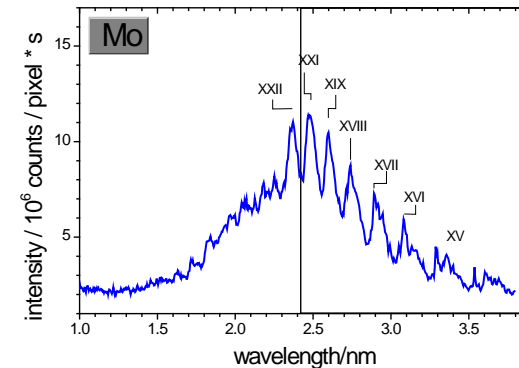


3.2 VLSG spectrograph

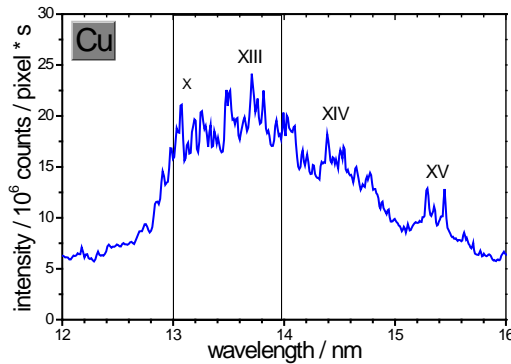
XUV: 1 nm region



XUV: water window



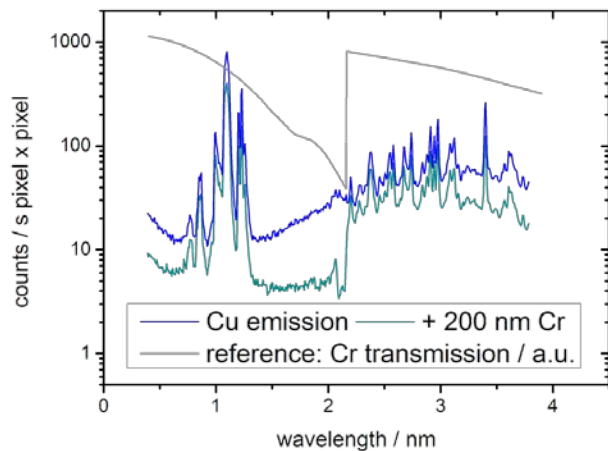
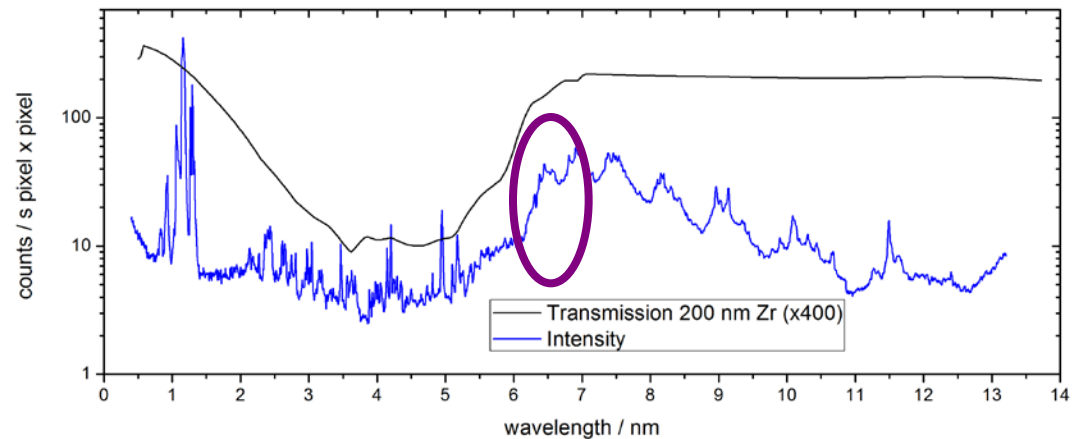
EUV: 13.5 nm region



	XUV 1 nm region	XUV water window	EUV 13 nm region
target	Cu	Mo	Cu
ph/ s sr line	$8 \cdot 10^{12}$	$6 \cdot 10^{14}$	$2 \cdot 10^{14}$
ph/s mrad ² mm ² line	10^{10}	$7 \cdot 10^{11}$	$3 \cdot 10^{11}$

3.2 TG spectrograph

Broadband source:
Filter calibration
XANES/NEXAFS
Selection of suitable
energy



	XUV 1 nm region	XUV water window	EUV 13 nm region	EUV 6.5 nm region
target	Cu	Mo	Cu	Cu
ph/ s sr line	$8 \cdot 10^{12}$	$6 \cdot 10^{14}$	$2 \cdot 10^{14}$	$1 \cdot 10^{14}$
ph/s mrad ² mm ² line	10^{10}	$7 \cdot 10^{11}$	$3 \cdot 10^{11}$	$2 \cdot 10^{11}$

3.2 Current setup



Laser in clean room
environment

Flexible design with two
beamlines and
changeable target material

Control
units

Plasma chamber with
beam propagation optics

TG spectrograph

Pinhole -
setup

Summary

1. Diode-pumped thin disk laser system

Compact and robust systems

High average power

High stability and beam quality

Flexible pulse duration for optimized plasma heating

2. LPP sources:

Liquid jet technology:

Low debris, intense line emission, different liquids

Cylinder target technology:

Broadband & line emission, different metals, high CE

Collaborations

1. Laser system



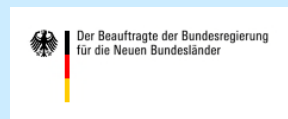
2. X-ray microscope



3. BLiX LPP source



4. Funding



Thank you for your attention!